

**PETITION FOR EXTENSION OF TIME UNDER 37 CFR 1.136(a)  
(Large Entity)**Docket No.  
AM1562D1In Re Application Of: **YIQIONG WANG**Serial No.  
09/882,141Filing Date  
June 15, 2001Examiner  
Umez-EroniniGroup Art Unit  
1765Invention: **METHOD OF ETCHING HIGH ASPECT RATIO OPENINGS IN SILICON****TO THE COMMISSIONER FOR PATENTS:**

This is a request under the provisions of 37 CFR 1.136(a) to extend the period for filing a response to the Office Action of February 25, 2003 above-identified application.  
*Date*

The requested extension is as follows (check time period desired):

☒ One month    ☐ Two months    ☐ Three months    ☐ Four months    ☐ Five months

from: May 25, 2003*Date*until: June 25, 2003*Date*

The fee for the extension of time is \$110 and is to be paid as follows:

- ☐ A check in the amount of the fee is enclosed.  
☒ The Director is hereby authorized to charge any fees which may be required, or credit any overpayment, to Deposit Account No. 13-4542  
☒ If an additional extension of time is required, please consider this a petition therefor and charge any additional fees which may be required to Deposit Account No. 13-4542

**BEST AVAILABLE COPY**  
*Signature*

Dated: May 29, 2003

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Please continue to send all correspondence to

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PO Box 450A

Santa Clara, CA 95052

I certify that this document and fee is being deposited on \_\_\_\_\_ with the U.S. Postal Service as first class mail under 37 C.F.R. 1.8 and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

*Signature of Person Mailing Correspondence***William R. Morris***Typed or Printed Name of Person Mailing Correspondence*

06/03/2003 VAUGBURN 00000002 134542 09882141

01 FC:1251 110.00 CH

cc: J. Bach

OFFICIAL

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<b>CERTIFICATE OF TRANSMISSION BY FACSIMILE (37 CFR 1.8)</b>			<b>Docket No.</b> AM1562D1
<b>Applicant(s):</b> YIQIONG WANG			
<b>Serial No.</b> 09/882,141	<b>Filing Date</b> June 15, 2001	<b>Examiner</b> Umez-Eronini	<b>Group Art Unit</b> 1765
<b>Invention:</b> METHOD OF ETCHING HIGH ASPECT RATIO OPENINGS IN SILICON			
<p>I hereby certify that this <u>Petition for Extension of time, in duplicate, and fee charged to Deposit Account</u> (Identify type of correspondence)</p> <p>is being facsimile transmitted to the United States Patent and Trademark Office (Fax. No. <u>703-872-9310</u>)</p> <p>on <u>May 29, 2003</u> (Date)</p> <p><u>Birgit E. Morris</u> (Typed or Printed Name of Person Signing Certificate)</p> <p><u>Birgit E. Morris</u> (Signature)</p> <p><b>Note:</b> Each paper must have its own certificate of mailing.</p> <p><b>BEST AVAILABLE COPY</b></p>			

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